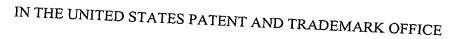


#7 IDS RABERD



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In re New Utility Application of		
Shunpei YAMAZAKI et al)	
Japanese Priority No.: 2000-012148) Attn: Applications	
Japanese Priority Date: January 20, 2000) Branch	
For: METHOD OF MANUFACTURING A) Date: January 18, 2000	
SEMICONDUCTOR DEVICE)	

INFORMATION DISCLOSURE STATEMENT

Honorable Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the reference(s) listed on the attached Form PTO-1449 be made of record in the above-identified application.

At least some of the references listed on the attached PTO-1449 are discussed in the specification of the subject application.

Copies of the references are submitted herewith in accordance with 37 C.F.R. 198(a).

U.S. Patent Nos. 5,643,826 and 5,923,962 are listed in the patent family of Japanese Patent-Laid-Open No. 07-130652.